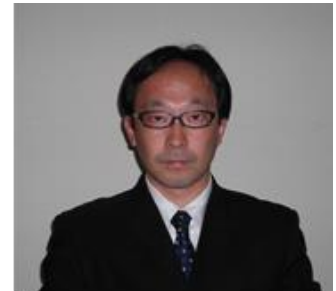


2014 International Workshop on EUVL

Keynote Presenter

Takayuki UCHIYAMA

Takayuki UCHIYAMA is Chief Specialist of Lithography Process Technology Department, Center For Semiconductor Research & Development, TOSHIBA Corporation. He joined TOSHIBA Corporation in 2012 and has been involved in the research and development of the next generation lithography. He has 25 years of experience in lithography process development.



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